Nanomaterials and Nanomanufacturing Research Center

NNRC FACILITIES ACCESS REQUEST FORM

USF UNIVERSITY OF SOUTH FLORIDA

For External User

NOTE: RETURN ALL PAPERWORK TO NTA102.

REQUESTOR'S NAME (print): _____
Last First MI

PREVIOUS NNRC ACCESS? _____ YES _____ NO IF YES, PREVIOUS Company: _____

COMPANY NAME: _____

Company Main Phone Number: _____

USF ID #: (starts with **U**) _____

USF ID (starts with) # 640013000: _____

COMPANY BILLING ADDRESS: _____

CITY/STATE/ZIP: _____

HOME PHONE / CELL PHONE: _____/_____

OFFICE PHONE / OFFICE LOCATION: _____/_____

E-MAIL ADDRESS*: _____

- You must complete NNRC Orientation; complete the Memorandum of Cooperative Agreement Nanotech Facility Affiliates (NFA) form before beginning training at Nanomaterials and Nanomanufacturing Center
- Purchase a USF ID ($15.00).
- For visitor parking instruction please go to the following link: http://cwta.fmhi.usf.edu/public/parking.htm

Card and tool access will be given once training session(s) have been successfully completed. You must have a valid USF ID card to gain access. Please provide for card access:

COMPLETED NON-EMPLOYEE HR FORM? YES _____ NO _____

I understand access to the NNRC facility is contingent upon my willingness to adhere to NNRC policies, procedures and general laboratory safety rules. In the event that I am found not to follow these policies, at the discretion of the Center's Director, I may lose access to this facility. Access revalidation is reviewed once per semester and verified with the director.

College of Engineering

Nanomaterials and Nanomanufacturing Research Center

TRAINING SESSIONS REQUEST

You should sign up for training around the time that you plan to use the equipment.

Professor initials	Training ID	Description of Training	# Sessions required	Seat capacity per Session	Duration of each Session	Total Training length	Prerequisite or Recommended	Offering Cycle (All normally offered once per month unless noted)
	C-CST	Cleanroom Safety	1	10	2 hours	2 hours		
	C-KSA	Karl Suss Mask Aligner	1	4	2 hours	2 hours	C-CST	
	C-ALP	Alphastep Profilometer	1	5	1 hour	1 hour	C-CST	
	C-PAX	PAX-IT Video capture & measurement	1	5	1 hour	1 hour	C-CST	
	C-SPL	Cleanroom Laurel Spinner	1	4	1 hour	1 hour	C-CST	
	C-PRC	Cleanroom Lithography/Metrology Techniques	1	4	4	4 hours	All the above	
	C-SPC	Cookson Spinner	1	4	1 hour	1 hour	C-CST	
	C-PDE	Plasma Therm Dry Etch	1	4	2 hours	2 hours	C-CST	
	C-DRIE	Deep Reactive Ion Etcher	1	5	4 hours	4 hours	C-CST	Once every 2 months
	C-BTI	Bruce Furnace Operator Training	3	4	2 hr/each	6 hours	C-CST	Once every 2 months
	C-PRO	Bruce Furnace Programming	2	2	2 hours	4 hours	C-CST, C-BTI, SC1/SC2	Once every 2 months
	C-DEK	Dektak 150 Profilometer	1	5	2 hours	2 hours	C-CST	
	C-NAN	Nanospec - Film Thickness Reflectivity	1	5	1 hour	1 hour	C-CST	
	C-QUI	Quintel Mask Aligner	1	4	2 hours	2 hours	C-CST	
	C-RUD	Rudolph Ellipsometer	1	5	1 hour	1 hour	C-CST	
	C-SOP	Sopra Ellipsometer	1	5	1 hour	1 hour	C-CST	
	C-WET	Fineline Wetbench	1	4	1 hour	1 hour	C-CST	
	C-TAN	Tanner Ledit Layout tools	1	10	2 hours	2 hours		
	C-MPG	Mask making at NNRC - Design Rules and Fracturing	1	10	1 hour	1 hour	C-TAN	
	C-MET	Mask Developing, Etching Stripping Techniques	1	4	1 hour	1 hour	C-CST	
	C-CRI	Critical Point Dryer Operation	1	4	1 hour	1 hour	C-CST	
	M-AFM	Atomic Force Microscope	3	4	3 hr/each	9 hours		
	M-FIBI	Focused Ion Beam - Imaging	5	4	1 @ 2 hours 4 @ 4 hours	18 hours	Recommend M-HSI	Once every 2 months
	M-FIBP	Focused Ion Beam - Processing	3	4	2 @ 4 hours 1 @ 8 hours	16 hours	M-FIBI	Once every 2 months
	M-FIBT	Focused Ion Beam - TEM Prep			3 @ 8 hours	24 hours	M-FIBI, M-FIBP	Once every 2 months
	M-HSI	Hitachi SEM Imaging	3	4	4 hr/each	12 hours		Once every 2 months
	M-HSE	Hitachi SEM EDS	3	4	4 hr/each	12 hours	M-HSI	Once every 2 months
	M-HSM	Hitachi SEM EDS Mapping	1	4	4 hr/each	4 hours	M-HSI, M-HSE	
	M-JSI	Jeol SEM Imaging	3	4	4 hr/each	12 hours		Once every 2 months
	M-JSL	Jeol SEM Litho	3	4	4 hr/each	12 hours	M-JSI & M-HSI	Once every 2 months
	M-HUM	Hummer X sputter	1	4	1 hour	1 hour	T-CYL,Co-req. with M-HSI#1	
	M-LTZ	Lietz Optical Microscope	1	5	.50 hour	.5 hour		
	M-TEM	Transmission Electron Microscope Techniques	8	4	3 @ 4 hours 3 @ 2 hours 2 @ 3 hours	24 hours	Recommend M-HSI, M-HSE, M-FIBI	Once every 2 months
	M-XRD	XRD Powder Diffraction Data Collection Techniques	3	4	2 hr/each	6 hours		
	M-HSI	Phillips Highscore and Powder Diffraction Database	1	4	2 hours	2 hours	M-XRD	
	M-GIX	XRD Thin Film GIXRD Techniques	1	4	2 hours	2 hours	M-XRD	
	M-XRR	XRD Thin Film Reflectivity Techniques	1	4	2 hours	2 hours	M-XRD	
	P-DEK	Dektak Profilometer	1	5	1 hour	1 hour		
	P-TST	General CV/ IV probe station + ICS software	1	5	1 hour	1 hour		
	P-TSS	Specific Test Instrument 4140B, 4284A, 4145B	1	5	1 hour	1 hour	P-TST	
	P-WBS	K&S Wire Bonder + Techniques	1	5	2 hours	2 hours		
	T-ALE	Aluminum Evaporator	2	4	4 hr/each	8 hours	C-ALP OR P-DEK	
	T-CRC	CRC Sputter Tool	1	4	2 hours	2 hours	T-CYL	
	T-CYL	General High Pressure gas bottle safety	1	6	1 hour	1 hour		
	T-EBE	E-beam Evaporator	2	6	4 hr/each	8 hours	C-ALP OR P-DEK	
	T-RTP	RTP Anneal	1	4	1 hour	1 hour	T-CYL	
	T-SFI	SFI Sputter	2	6	4 hr/each	8 hours	T-CYL	
	W-DICE	Dicing Saw	1	5	3 hours	3 hours		
	W-SPI	Integrated Tech Spinner (Outside the Cleanroom)	1	4	1 hour	1 hour		
	W-WET	General Wet Chemistry in NTA 104	1	4	1 hour	1 hour	W-WET	
	N-ORI	Orientation for New Nanotech User	1	10	.5 hours	.5 hours		Once a week

Legend	
	Required for all New Users
	XRD Trainings
	FIB/TEM Trainings

Legend	
	SEM Core Trainings
	Mask Making & Layout
	Micro Lithography Core

RETURN THIS FORM TO SCLAFANI LOUIS-JEUNE IN NTA0102.

Requestor's Name/Signature & Date_____

Print Last Name Signature Date